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FORM PTO-1449 (Modified)		Attorney Docket No.: 19930-002800US		Application No.: 10/087,040	
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION AND DISCLOSURE STATEMENT (Use several sheets if necessary)		Applicant: David Miller et al.		Filing Date: February 28, 2002	
		Group: Unassigned		2834	
Reference Designation		U.S. PATENT DOCUMENTS			
Examiner Initial	Document No.	Date	Name	Class	Sub-class
AA	5,414,540	05/09/95	Patel et al.	359	39
AB	5,917,625	06/29/99	Ogusu et al.	359	130
AC	5,999,672	12/07/99	Hunter et al.	385	37
AD	6,028,689	02/22/00	Michalicek et al.	359	224
AE	6,040,935	03/21/00	Michalicek	359	198
AF	6,097,859	08/01/00	Solgaard	385	17
AG	6,108,471	08/22/00	Zhang et al.	385	37
AH	6,128,122	10/03/00	Drake et al.	359	224
AI	09/442,061		Weverka, et al.		
AJ					
AK					
FOREIGN PATENT DOCUMENTS					
	Document No.	Date	Country	Class	Sub-class
AL					
AM					
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)					
AN	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110				
AO	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978				
AP	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992				
AQ	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96				
AR	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999				
AS	J. Gradé et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100				
AT	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65				
AU	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987				
AV	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985				
AW	P. Phillippe et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985				
AX	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986				
AY	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998				

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Examiner: Thomas M. Dougherty, December 1, 2003



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<u>TMD</u> AZ	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202		
<u>TMD</u> BA	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem.Soc., Vol. 142, No. 6, June 1995		
<u>TMD</u> BB	P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704		
<u>TMD</u> BC	Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998		
<u>TMD</u> BD	Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000		
BE			
EXAMINER <u>Thomas M. Dougherty</u>	DATE CONSIDERED <u>December 1, 2003</u>		

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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.